

REPORT DOCUMENTATION PAGE				Form Approved OMB No. 0704-0188	
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1. REPORT DATE (DD-MM-YYYY) 07-06-2010		2. REPORT TYPE Conference Proceeding		3. DATES COVERED (From - To) 12/18/08-7/6/10	
4. TITLE AND SUBTITLE Multilayer Anti-Reflective Coating Development for PMMA Fresnel Lenses				5a. CONTRACT NUMBER NNX09CB36C	
				5b. GRANT NUMBER	
				5c. PROGRAM ELEMENT NUMBER	
6. AUTHOR(S) Don Patterson, Keith Jamison, and Byron Zollars				5d. PROJECT NUMBER	
				5e. TASK NUMBER	
				5f. WORK UNIT NUMBER	
7. PERFORMING ORGANIZATION NAME(S) AND ADDRESS(ES) Nanohmics, Inc. 6201 East Oltorf St. #400 Austin, TX 78741				8. PERFORMING ORGANIZATION REPORT NUMBER	
9. SPONSORING / MONITORING AGENCY NAME(S) AND ADDRESS(ES) NASA Marshall Space Flight Center Huntsville, Al 35812				10. SPONSOR/MONITOR'S ACRONYM(S) NASA MSFC	
				11. SPONSOR/MONITOR'S REPORT NUMBER(S)	
12. DISTRIBUTION / AVAILABILITY STATEMENT DISTRIBUTION STATEMENT A: Approved for public release; distribution is unlimited.					
13. SUPPLEMENTARY NOTES Presented at Mirror Technology Days, Boulder, Colorado, USA, 7-9 June 2010.					
14. ABSTRACT Anti-reflective (AR) coatings comprised of several layers of oxide and nitride dielectric materials have successfully been sputter deposited on UV transparent polymethylmethacrylate (UVT-PMMA) windows. The amorphous coatings are deposited using reactive sputtering in a custom-designed magnetron sputtering tool. The AR coatings are adherent, radiation hard, and improve the transmission of UVT-PMMA windows by approximately 5% in the 300-450 nm range. The coatings will be applied and tested on UVT-PMMA Fresnel lenses for use in space-borne telescopes.					
15. SUBJECT TERMS Anti-reflective coatings, Fresnel lens, polymethylmethacrylate, PMMA					
16. SECURITY CLASSIFICATION OF:			17. LIMITATION OF ABSTRACT SAR	18. NUMBER OF PAGES 20	19a. NAME OF RESPONSIBLE PERSON Hans-Peter Dumm
a. REPORT UNCLASSIFIED	b. ABSTRACT UNCLASSIFIED	c. THIS PAGE UNCLASSIFIED			19b. TELEPHONE NUMBER (include area code) 505-853-8397



Multilayer Anti-Reflective Coating Development for PMMA Fresnel Lenses

Don Patterson, Keith Jamison, and Byron Zollars

Mirror Technology SBIR/STTR Workshop

Boulder, CO

June 7, 2009

Radiation Hard Multilayer Optical Coatings

SBIR Phase II Contract

NNX09CB36C

COTR: Bill Jones

Marshall Space Flight Center

Space ready multi-layer optical coatings

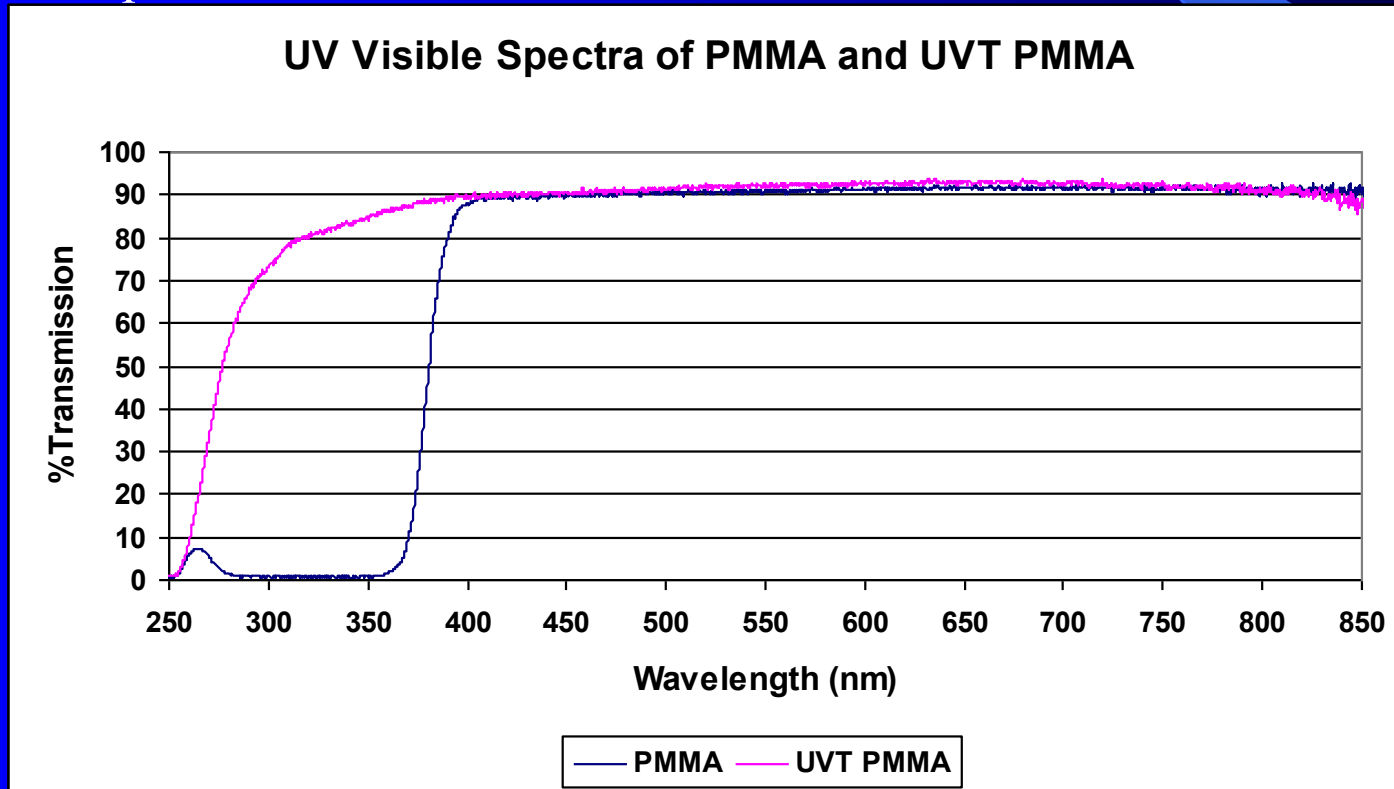
Problem: New optical coatings need to be developed for next generation light weight space base optics for use in programs such as NASA's EUSO observatory

Phase II Goal: Develop a robust anti-reflective coating that can be applied to UVT-PMMA Fresnel lenses

Nanohmics' Approach: Multi-layer amorphous nitrides / oxides as optical coating

Why PMMA?

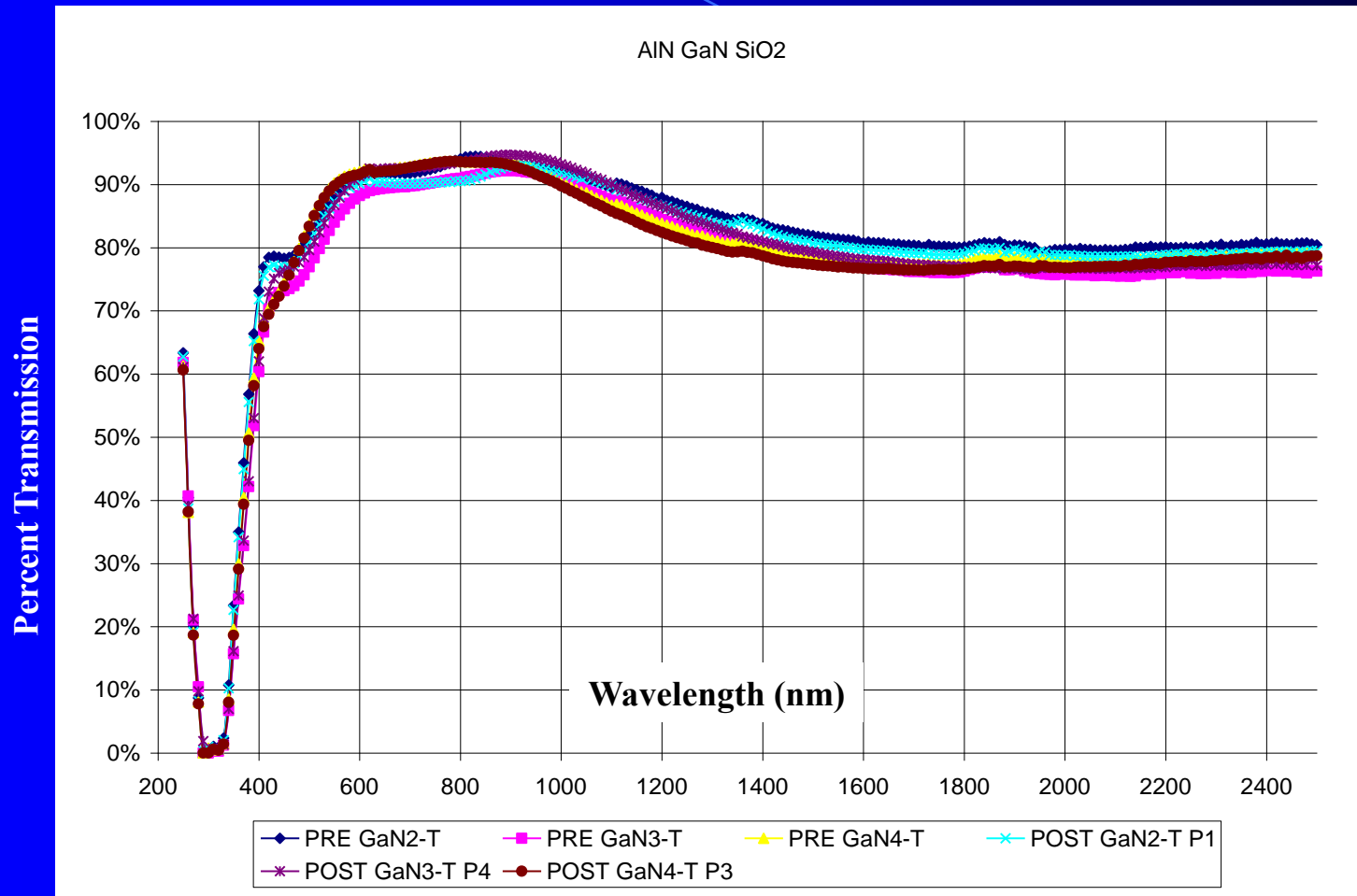
- Light weight
- UV Resistant
- UV Transparent
- Inexpensive



Advantages of Amorphous Oxides and Nitrides

- Proven radiation resistance to darkening
- Can be used to design anti-reflection, reflective, and band pass coatings
- Room temperature deposition
- Adhere well to most materials
- Robust coating

Radiation Hardness

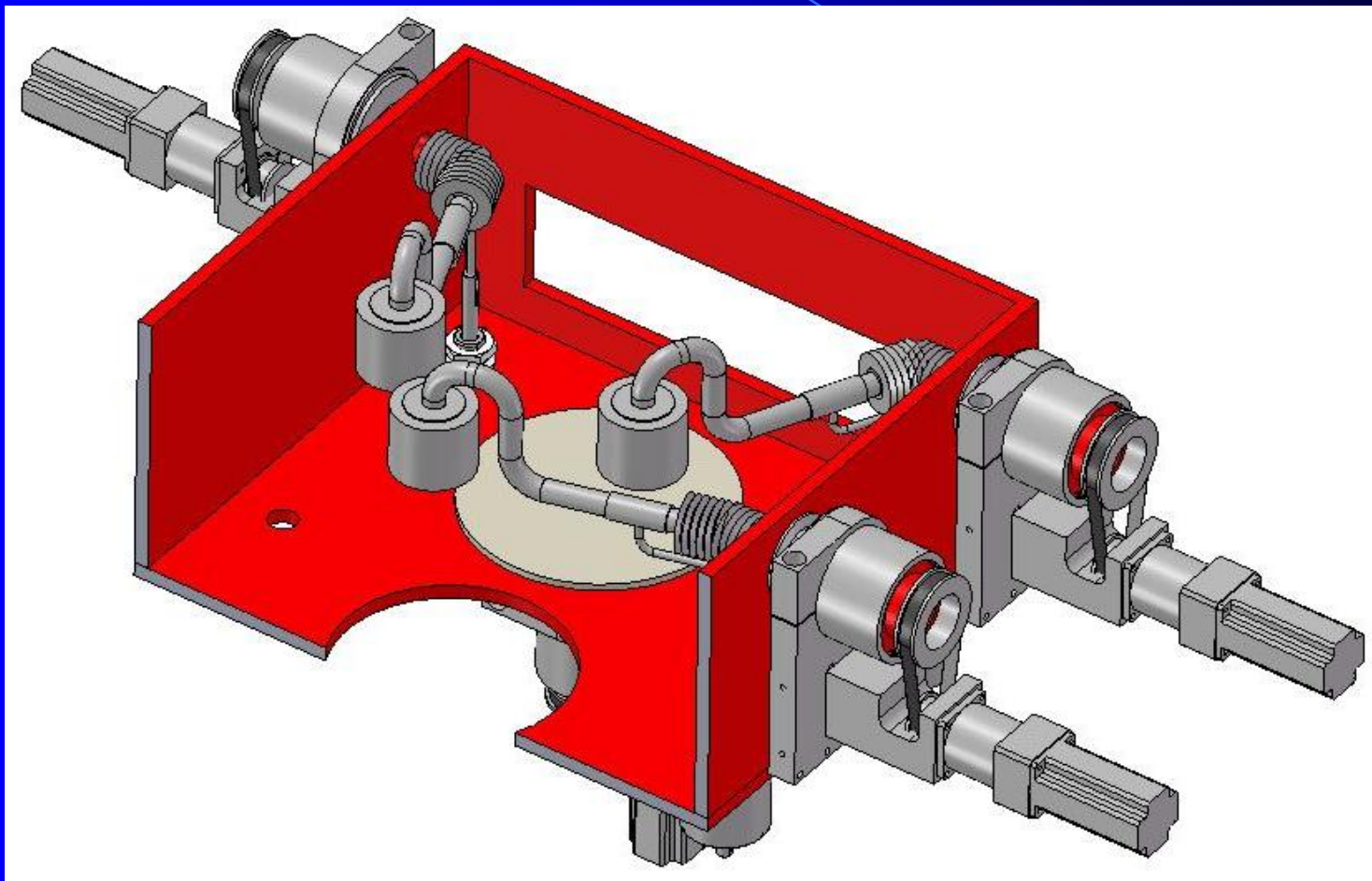


Multi-layer nitride / oxide coating exposed to $\sim 10^{15}$ protons/cc flux
at 20 keV, 50 keV, 100 keV and 300 keV

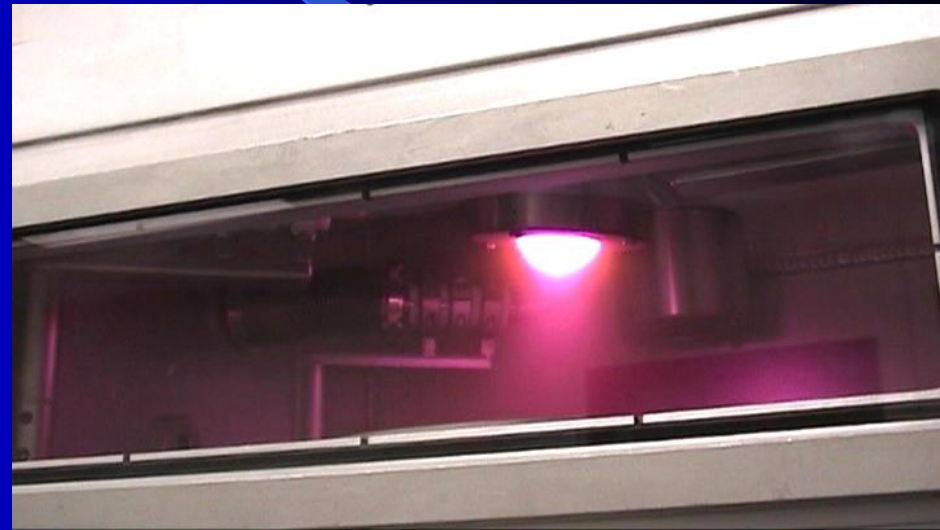
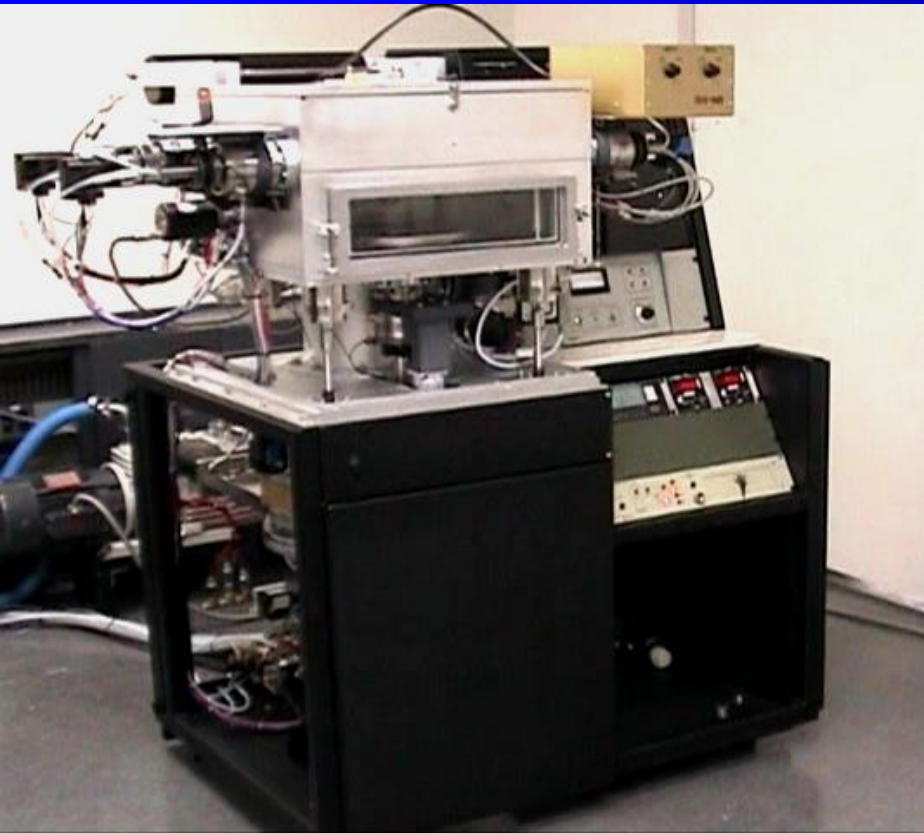
Advantages of Sputter Deposition

- Able to deposit optical quality films
- Reactive growth of nitrides and oxides results in relatively fast deposition rates
- Sputter process results in higher density, better adhesion coatings compared to e-beam deposition
 - Bias sample if increased density desired
- Deposit on cooled substrates
- Large established infrastructure
- Relatively inexpensive process that can handle large substrates (12" dia. in our system)

New Deposition System



Sputter Deposition System



Amorphous Nitride / Oxide Growth

- Coating materials: AlN, ZrO₂, and SiO₂
- All materials grown using reactive sputtering
 - Solid target (Al, Zr, Si)
 - Background gas (Ar:O₂ or Ar:N₂)
- RF power = 200 W
- Growth rates ~1.7-7.7 nm/min
- Thickness measured using optical methods (Filmetrics F20) and profilometry (Dektak)
- No delamination noted after thermal cycling (-55 °C to 75 °C)

Growth Rate and Adhesion Strength

Growth rate of SiO_2 , AlN , and ZrO_2 at 200 W RF power.

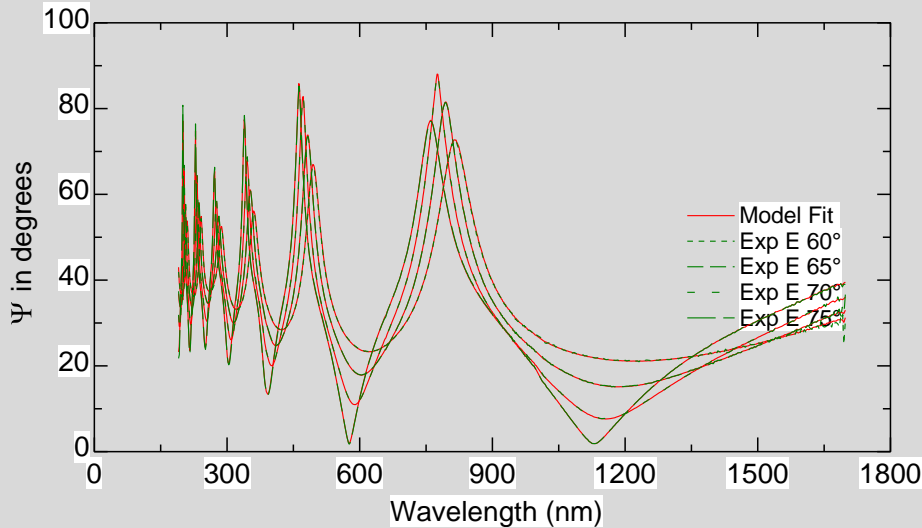
Material	Growth Rate
SiO_2	7.7 nm/min
AlN	2.4 nm/min
ZrO_2	1.7 nm/min

Adhesion strength to PMMA

	AlN	SiO_2	ZrO_2
Max Adhesion Force (Kg)	4.7	3.0	1.0
Max Adhesion Strength (Kg/cm^2)	83	52	18

Optical Constant Data

Generated and Experimental

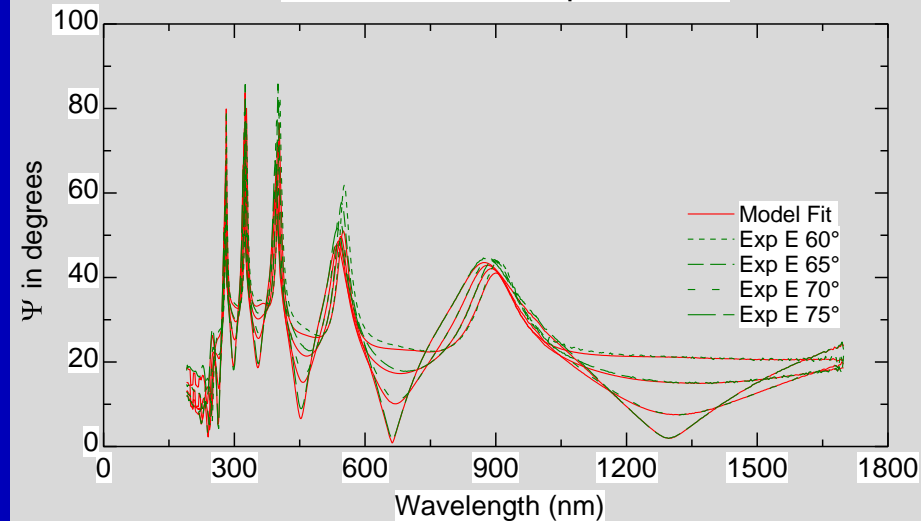


SiO_2

- At 500 nm:

- AlN ($n=1.973$, $k=0.0004$)
- ZrO_2 ($n=2.10$, $k=0.0002$)
- SiO_2 ($n=1.47$, $k=0.0007$)

Generated and Experimental



AlN

Stress

AR Coatings at 200 W; 500x magnification

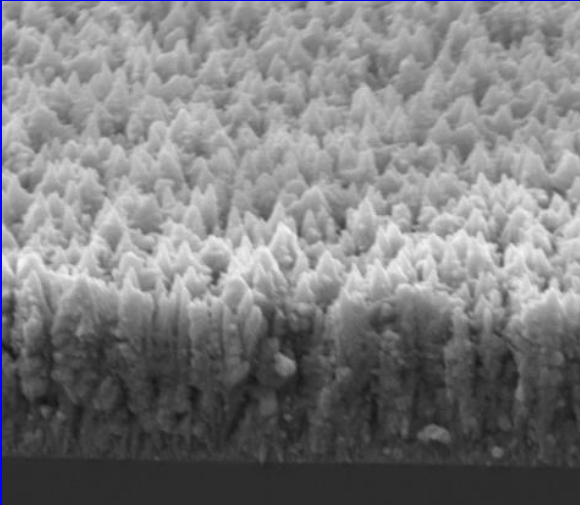


Old System

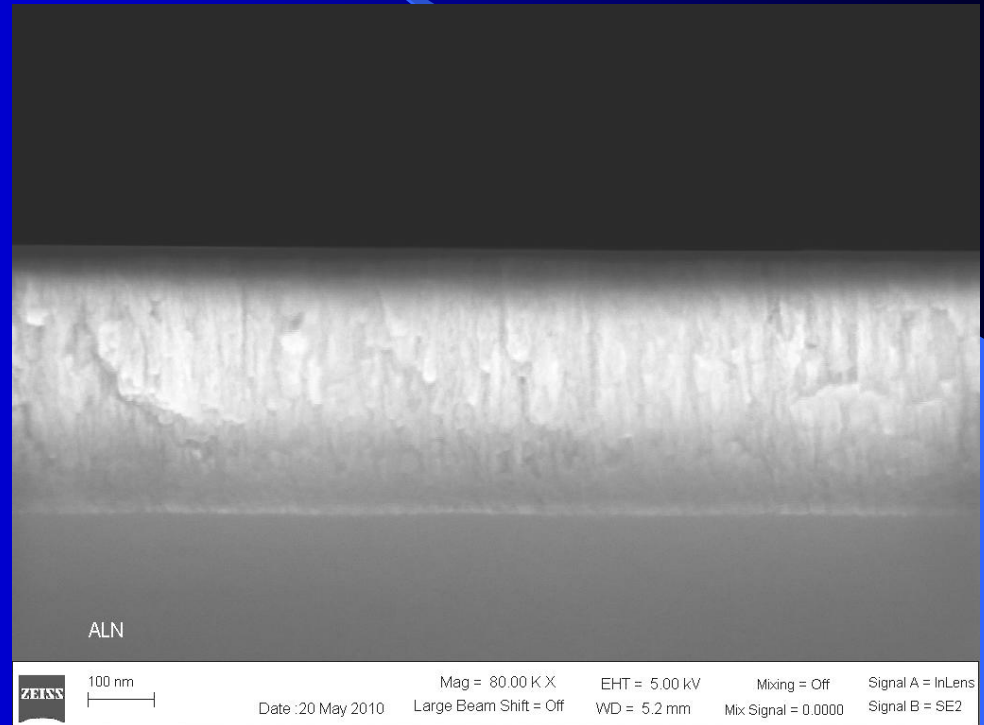


New System

Amorphous Films



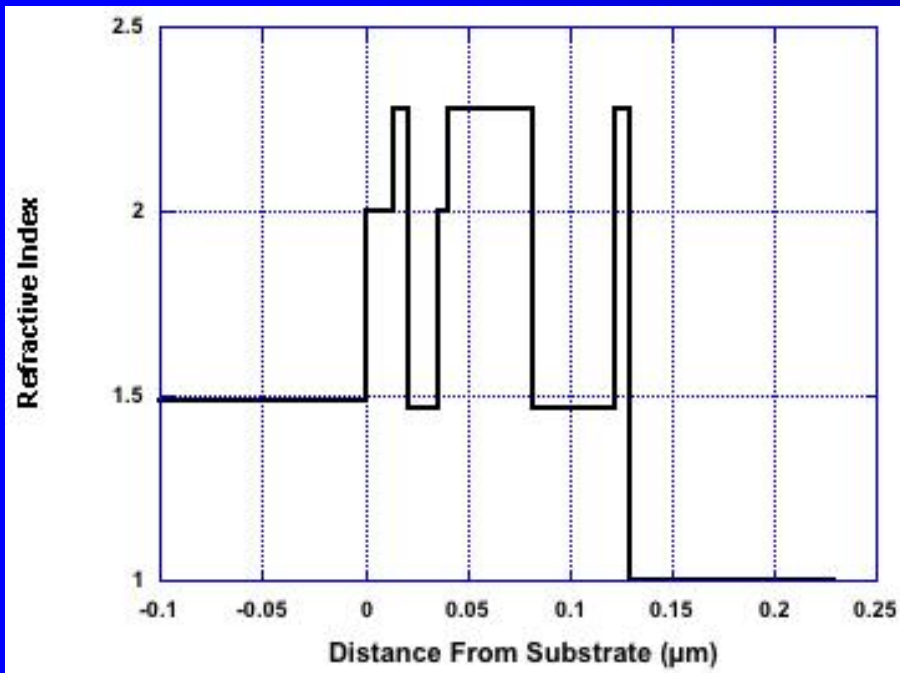
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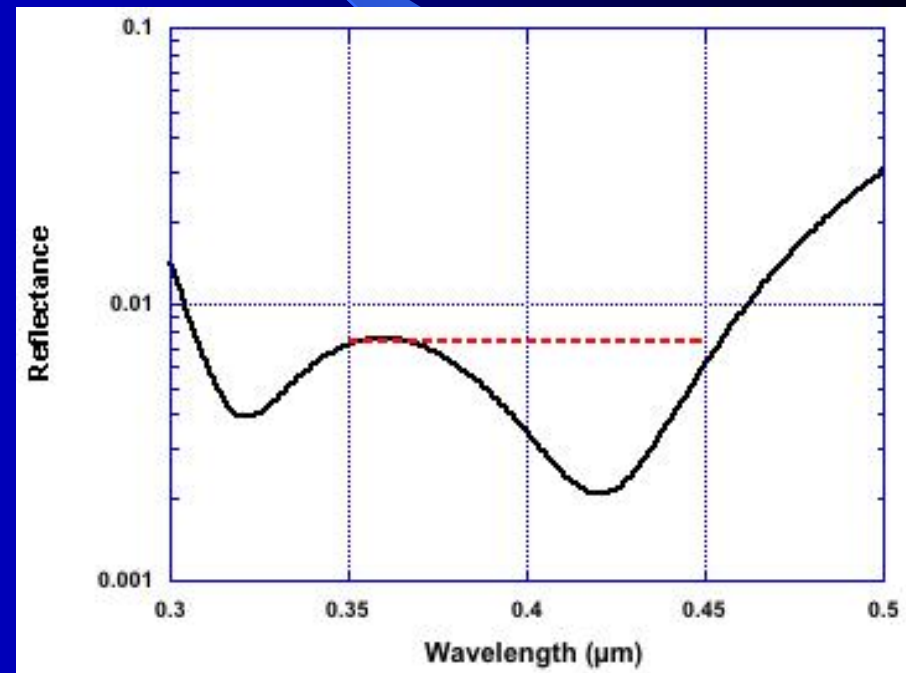
New System

Anti-Reflective Coating Model

SiO_2 , AlN, and ZrO_2



Prescription

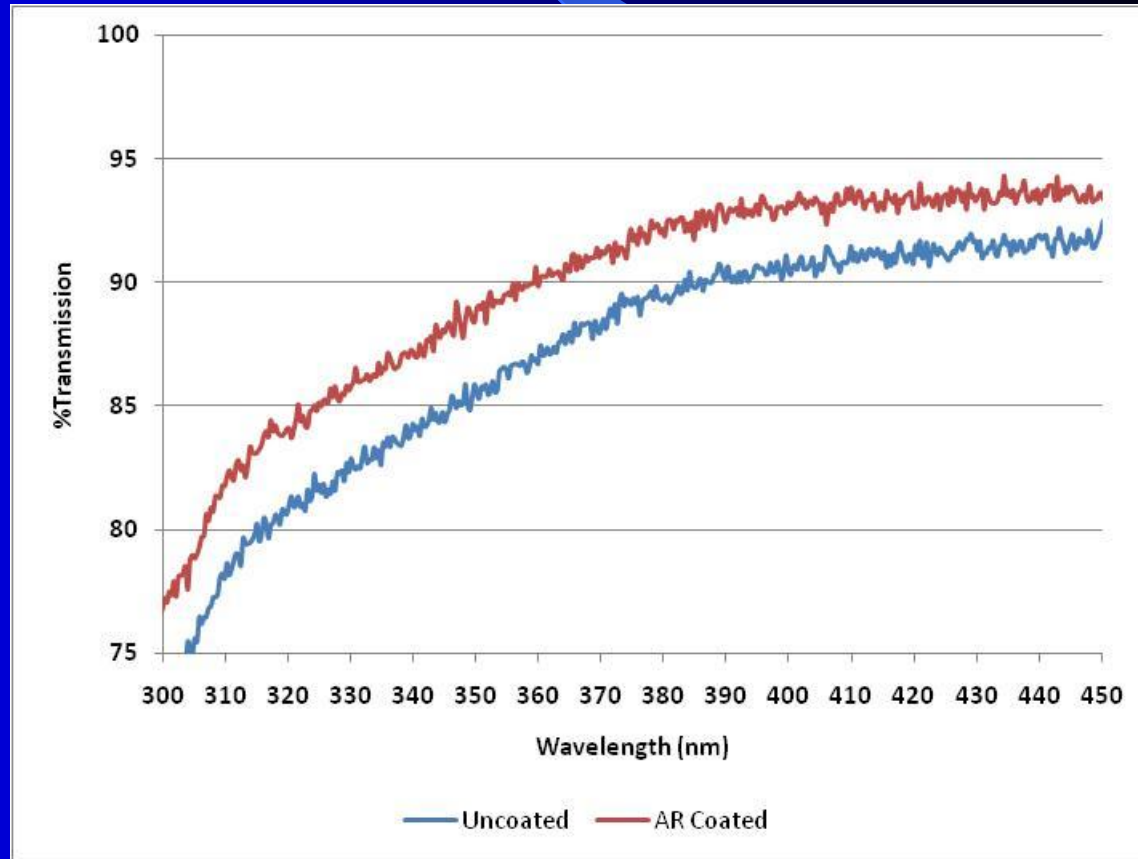
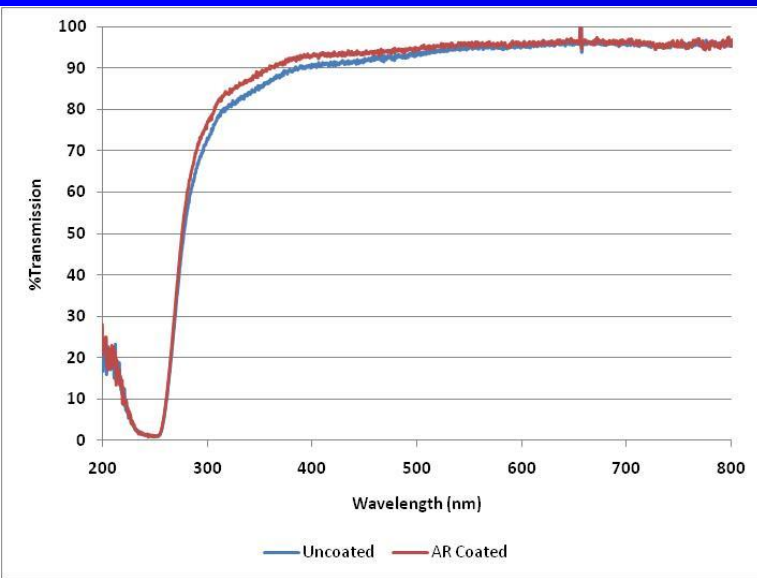


Anticipated Spectrum

AR Coated UVT PMMA

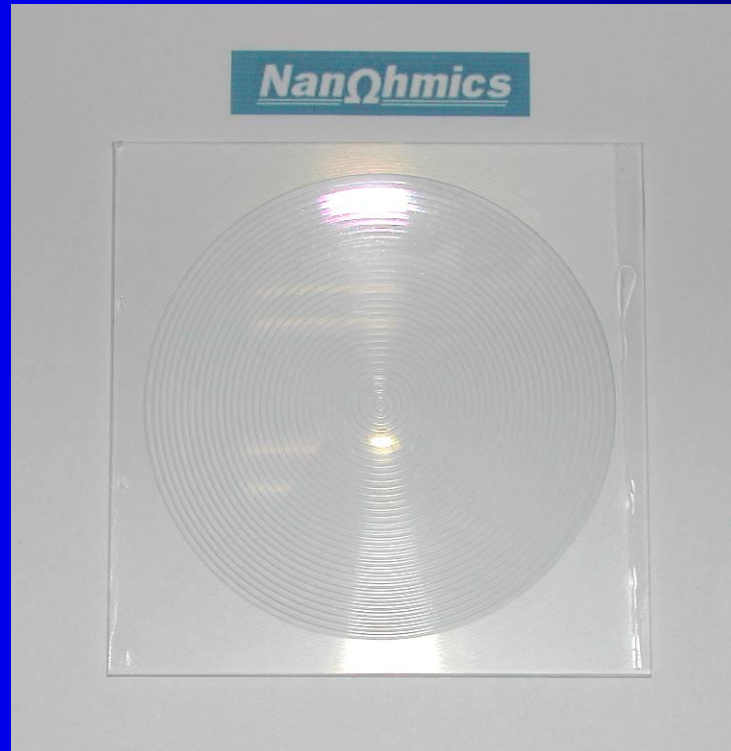


AR Coated UVT PMMA



Current Status / Results

- Designed and implemented new deposition
- Measured n and k for amorphous materials
- Stress eliminated in the films
- Initial AR coatings look promising



Future Work

- Improve models with new data
- Qualify new deposition tool
 - Deposition parameters
 - Coating uniformity (now at 90% uniformity)
- Deposition on Fresnel lenses
- Environmental Testing
 - Humidity
 - Temperature cycling
 - UV exposure

Multilayer Anti-Reflective Coating Development For PMMA Fresnel Lenses

***Nanohmics, Inc.
Austin, TX***

INNOVATION

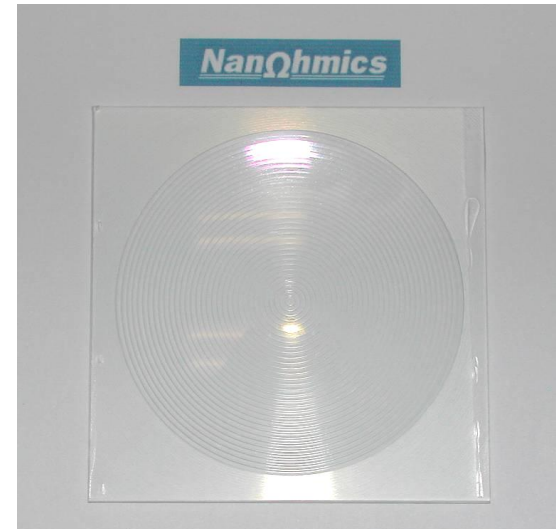
Nanohmics is developing a robust, radiation-hard, anti-reflective coating for use on polymeric Fresnel lenses.

ACCOMPLISHMENTS

- ◆ Novel deposition system designed , fabricated, and implemented
- ◆ Low stress, high quality dielectric materials deposited on a variety of substrates including polymethylmethacrylate (PMMA)
- ◆ Highly amorphous films achieved
- ◆ Excellent adhesion to most materials
- ◆ 90% uniformity achieved

COMMERCIALIZATION

- ◆ Primary markets for the coatings include optics, tooling, and ceramics.
- ◆ Presently using the technology to increase the strength of ceramic drilling materials.
- ◆ Sales from the technology have reached \$12,500. If successful, a revenue stream of 2% gross is expected from our partner.
- ◆ Exploring partnerships with optics manufacturers.



AR Coated PMMA Fresnel Lens

GOVERNMENT/SCIENCE APPLICATIONS

- ◆ Technology being developed for use in the Extreme Universe Space Observatory (EUSO).
- ◆ Coatings still must be fully tested.
- ◆ Technology can be used for any number of robust , hard coatings especially for optical materials.
- ◆ Polymeric lenses will result in a lower launch weight and enhanced savings over using glass lenses.

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2009 SBIR Phase II: NNX09CB36C